



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICATION NO.: 10/664,247

APPLICANT(S): Diane K. Stewart, J. David Casey Jr., John Beaty, Christian R. Musil, and

Steven Berger

FILING DATE: 09/17/2003

TITLE: Photolithography Mask Repair

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, Va 22313-1450

Pursuant to the guidelines for Information Disclosure Statements, 37 C.F.R. §§ 1.97-1.98, attached hereto is PTO Form 1449 (one sheet) with references listed for consideration by the Office.

In accordance with 37 C.F.R. § 1.98(a), copies of the listed written references are being provided.

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This Information Disclosure Statement is being filed before the mailing of a first Office action on the merits.

Respectfully submitted,

Date: 2/12/04

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Complete if Known				
Application Number	10/664,247			
Filing Date	09/17/2003			
First Named Inventor	Diane K. Sewart			
Art Unit		-		
Examiner Name				
Attorney Docket Number	F118 B			

			U. S. PATENT	DOCUMENTS	
Examiner Initials*	Cite No.1	Document Number Number-Kind Code ^{2 (# known)}	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	A	US- 6,365,896	04-02-2002	Van der Mast	i igaico / tipicai
	L	0,303,690			
	В	^{US-} 6,184,525	02-06-2001	Van der Mast	
	С	^{US-} 6,172,363	01-09-2001	Shinada et al.	
	D	^{US-} 5,578,821	11-26-1996	Meisberger et al.	
		US-			-
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FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No.1	Foreign Patent Document	Publication Date	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages	
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)	MM-DD-YYYY	,	Or Relevant Figures Appear	ד
	E	05-174768	07-13-1993	Nikon Corp.		
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	STAT	EMENT	BY A	PPLICANT	First Named Inventor	Diane K. Sewart	
					Art Unit		
		(Use as many s	neets as ne	ecessary)	Examiner Name		
	Sheet	2	of	2	Attorney Docket Number	F118 B	

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_		NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
•	F	C.K. CRAWFORD, Charge Neutralization Using Very Low Energy Ions, Scanning Electron Microscopy, 1979, II, SEM INc., USA	
	G	ALBERT FOLCH ET AL., High Vacuum Versus, "Environmental" Electron Beam Deposition, Jul/Aug. 1996, B 14(4), PP. 2609-2614, J. Vac. Sci.	
	н	YUKINORI OCHIAI, Electron-Beam-Induced Deposition of Copper with Low Resistivity, Nov/Dec. 1996, B 14(6), PP. 3887-3891, J. Vac. Sci. Technol	
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Examiner	Date
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